What is claimed is:

- 1 1. An assembly, comprising:
- a die, the die having a body comprising a first material; and
- an interposer having a first side and a second side, the die coupled to the
- 4 first side of the interposer;
- wherein the interposer comprises the first material, and the first side is
- 6 electrically and mechanically coupled to the die.
- 1 2. The structure of Claim 1, further comprising circuit elements embedded
- within the interposer.
- 1 3. The structure of Claim 2, wherein circuit elements comprise capacitors.
- 1 4. The structure of Claim 2, wherein circuit elements comprise transistors.
- 1 5. The structure of Claim 1, wherein capacitors and transistors are
- 2 incorporated into the interposer.
- 1 6. The structure of Claim 1, further comprising a circuit substrate coupled to
- the second side of the interposer.

- 1 7. The structure of Claim 6, wherein the die is coupled to the interposer by
- 2 solder bumps, and the interposer is coupled to the circuit substrate by solder.
- 3 balls.
- 1 8. The structure of Claim 7 wherein the solder bumps have a first pitch, the
- 2 solder balls have a second pitch, and the second pitch is greater than the first
- 3 pitch.
- 1 9. The structure of Claim 1, wherein the interposer has a first interconnection
- 2 pitch on the first side, and a second interconnection pitch on the second side,
- and the second interconnection pitch is greater than the first interconnection
- 4 pitch.
- 1 10. An assembly comprising:
- an integrated circuit formed on a silicon substrate;
- an interposer having a first surface and an opposing second surface; and
- 4 a circuit substrate;
- wherein the interposer is disposed between the integrated circuit and the
- 6 circuit substrate, and the interposer comprises silicon.
- 1 11. The assembly of the Claim 10, wherein the interposer is electrically and
- 2 mechanically coupled to the integrated circuit.

- 1 12. The ass mbly of Claim 11, wherein the interposer is coupled to the
- 2 integrated circuit by a plurality of solder bumps.
- 1 13. The assembly of Claim 11, wherein the interposer is coupled to the circuit
- 2 substrate by a plurality of solder balls.
- 1 14. The assembly of Claim 10, further comprising electrical circuits
- 2 incorporated into the interposer.
- 1 15. The assembly of Claim 14, wherein the electrical circuits comprise
- 2 electrostatic discharge protection circuits.
- 1 16. The assembly of Claim 14, wherein the electrical circuits comprise buffer
- 2 circuits.
- 1 17. The assembly of Claim 14, wherein the electrical circuits comprise
- 2 memory circuits.
- 1 18. An electronic assembly comprising:
- a die having a silicon substrate;
- 3 an interposer having a silicon substrate with a first surface and an
- 4 opposing second surface, the first surface attached to the die by solder bumps;
- 5 and

- a circuit substrate attached to the second surface by sold r balls;
- wherein the interposer comprises circuit elements.
- 1 19. The electronic assembly of Claim 18, wherein the circuit elements
- 2 comprise active circuit elements.
- 1 20. The electronic assembly of Claim 18, wherein the circuit elements
- 2 comprise passive circuit elements.
- 1 21. The electronic assembly of Claim 18, wherein the circuit elements
- 2 comprise active and passive circuit elements.
- 1 22. The electronic assembly of Claim 21, wherein the active circuit elements
- 2 include at least one field effect transistor, and the passive circuit elements
- 3 include at least one capacitor.
- 1 23. The electronic assembly of Claim 18, wherein the die comprises a first
- 2 plurality of insulated gate field effect transistors having a first set of electrical
- 3 characteristics, the interposer comprises a second plurality of insulated gate field
- 4 effect transistors having a second set of electrical characteristics, and the first
- set of electrical characteristics are different from the second set of electrical
- 6 characteristics.

- 1 24. The electronic assembly of Claim 23, wherein the first set of electrical
- 2 characteristics includes a first gate dielectric breakdown voltage, the second set
- 3 of electrical characteristics includes a second gate dielectric breakdown voltage
- 4 and the second gate dielectric breakdown voltage is greater than the first gate
- 5 dielectric breakdown voltage.
- 1 25. The electronic assembly of Claim 18, wherein the die and the interposer
- are electrically coupled through the solder bumps, and a first power supply node
- of the die is coupled to a first terminal of a capacitor disposed on the interposer,
- 4 and a second power supply node of the die is coupled to a second terminal of
- 5 the capacitor.
- 1 26. A method of making an electronic assembly, comprising:
- 2 coupling an integrated circuit (IC) and an interposer; and
- coupling a circuit substrate and the interposer;
- 4 wherein the IC and the interposer each have a body substantially
- 5 comprising the same material, and wherein coupling comprises mechanically
- 6 attaching and electrically connecting.
- 1 27. The method of Claim 26, wherein the IC and the interposer each have a
- 2 body substantially comprising silicon, and wherein the circuit substrate comprises
- 3 a printed circuit board.

- 1 28. The method of Claim 26, furth r comprising forming circuit elements on
- 2 th interposer.
- 1 29. The method of Claim 26, further comprising incorporating circuit elements
- 2 into the interposer.
- 1 30. The method of Claim 29, wherein circuit elements comprise active and
- 2 passive circuit elements.
- 1 31. A method of making an interposer, comprising:
- forming an oxide layer on each of a first surface and a second surface of
- 3 a substrate;
- 4 patterning the oxide layer of the first surface so as to expose portions of
- 5 the substrate;
- 6 isotropically etching through a first portion of the exposed substrate to
- 7 form a first portion of a deep-via opening;
- 8 anisotropically etching through a second portion of the exposed substrate
- 9 to form a second portion of a deep-via opening;
- sputtering a copper barrier and a copper seed layer into the first and
- second portions of the deep-via opening;
- electroplating a conductive material over the seed layer to form a deep-
- 13 via; and

- forming vias and interconnect lines over the second surfac of the
- 15 substrate;
- wherein at least one interconnect line is electrically coupled to at least
- 17 one deep-via.